# 820 MW/cm<sup>2</sup> 3326 V 0.42 A/mm 選択ドープダイヤモンド MOSFET 820 MW/cm<sup>2</sup> 3326 V 0.42 A/mm Modulation Doped Diamond MOSFETs 佐賀大院エ<sup>1</sup>, アダマンド並木精密宝石(株)<sup>2</sup>

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### **<u>1. Introduction</u>**

Diamond is a promising semiconductor material for high power and high-frequency operation as it possesses a very high breakdown field and thermal conductivity. The hole sheet concentration of Hdiamond can be increased by using NO<sub>2</sub> doping up to ~1 × 10<sup>14</sup> cm<sup>-2</sup> [1] and can be passivated by using the Al<sub>2</sub>O<sub>3</sub> layer [2]. Recently, we demonstrated pchannel modulation-doped diamond MOSFETs with NO<sub>2</sub>-delta doping in the Al<sub>2</sub>O<sub>3</sub> layer for spatial separation of acceptor layer to improve mobility [3]. This study reports a very high voltage (3326 V) operation of modulation-doped diamond MOSFETs.

## 2. Growth and Fabrication

Diamond MOSFETs were fabricated on (001) high-quality heteroepitaxial diamond (Kenzan diamond<sup>®</sup>). An  $Al_2O_3$  layer was deposited on the H-diamond as the spacer layer. Then, NO<sub>2</sub> delta doping was performed on the spacer layer. Finally, an  $Al_2O_3$  /NO<sub>2</sub>/  $Al_2O_3$  was formed on the H-diamond sample.

#### 3. Results and Discussion

Figure 1 (a) shows the maximum drain current  $(I_{D,max})$  of 417 mA/mm and on-resistance of 82.2  $\Omega$ ·mm of modulation-doped diamond MOSFETs. From the capacitance characterization, a maximum

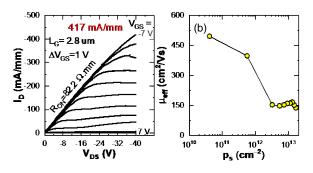


Fig 1. (a) DC output characteristics of modulation doped diamond MOSFET and (b) sheet-carrier density dependent effective mobility characteristics.

sheet concentration (p<sub>s</sub>) of  $1.66 \times 10^{13}$  cm<sup>-2</sup> was obtained. By eliminating the access resistance, p<sub>s</sub> dependent effective mobility ( $\mu_{eff}$ ) characteristic is shown in Fig. 1(b).  $\mu_{eff}$  at the high current region was almost constant (~150 cm<sup>2</sup>/Vs) and near the threshold maximum,  $\mu_{eff}$  becomes 497 cm<sup>2</sup>/Vs. A high breakdown voltage of 3326 V was measured as shown in Fig. 2. The specific on-resistance was 13.48 m $\Omega$ ·cm<sup>2</sup> and consequently, Baliga's figureof-merit (BFOM) was determined as 820 MW/cm<sup>2</sup>.

## 4. Conclusion

In conclusion, by using NO<sub>2</sub>-delta doping in the  $Al_2O_3$  layer technique, we have demonstrated the high voltage (3326 V) operation and high BFOM (820 MW/cm<sup>2</sup>) of modulation-doped diamond MOSFETs.

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#### References

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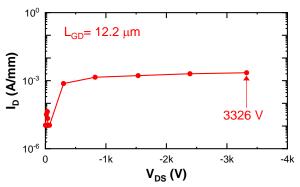


Fig. 2. Off-state breakdown voltages of modulation doped diamond MOSFET.